

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Goeran STEMME et al.
Title: RESONANT SENSOR AND METHOD OF MAKING A PRESSURE
SENSOR COMPRISING A RESONANT BEAM STRUCTURE
Divisional Appln
of Ser. No.: 09/219,794, filed December 23, 1998
Filing Date: December 12, 2000
Examiner: A. Aw-Musse
Art Unit: 2855

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination of the above-identified application, applicants respectfully
request that the following amendment be entered into the application:

IN THE TITLE:

Lines 1-2, delete "beam structure" and insert --Beam Structure--.

IN THE SPECIFICATION:

After the title, please insert, --This application is a divisional of 09/219,794, filed
December 23, 1998.--

Page 1, line 3, delete "invention" and insert --Invention--;
line 8, delete "o Related" and insert --of Related--; and
line 9, delete "i.a." and insert --for example--.

Page 2, line 11, before "pressure" insert --a--.

Page 3, line 1, after "e.g." insert --a--; and
line 27, delete "describe" and insert --described--.

Page 4, line 7, delete "illustrates" and insert --illustrate--;
line 21, delete "23" and insert --13--; and
line 24, delete "in" and insert --by--.

Page 5, line 10, after "circular" insert --,--; delete "comprises" and insert
--comprise--;

line 12, delete ".,";

line 17, delete "in" and insert --by--;

line 19, delete "diaphragm" and insert --beam--; delete "in" and
insert --by--; and

line 31, after "weak" insert --one--.

Page 6, line 7, delete "treble" and insert --trebles--; and
line 30, delete "in" and insert --by--.

Page 8, line 20, after "provide" insert --a--.

Page 9, line 22, delete "polysislicon" and insert --polysilicon--;

line 28, delete "piezoresitor" and insert --piezoresistor--; and

line 30, delete "piezoresitor" and insert --piezoresistor--.

IN THE CLAIMS:

Please cancel claims 14-23, allowed in the parent application. Remaining Claims 1-13 are to be examined.

IN THE DRAWINGS:

By way of a separate letter attached hereto, applicants submit copies of the Formal Drawings submitted in the parent application, Figures 1-18.

IN THE ABSTRACT:

Please add the Abstract attached hereto on a separate sheet.

REMARKS

If the Examiner has questions or comments the Examiner may contact the undersigned. Applicants request examination of the application and issue of an Office Action.

Respectfully submitted,

Date December 12, 2000

By 

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Abstract of the Disclosure

A resonant microbeam pressure sensor is disclosed, comprising a microbeam suspended by a diaphragm at one or more points by suspension elements. Pressure applied to the diaphragm will cause the resonance frequency of the beam to shift. This shift is detectable and proportional to the pressure. The device is manufactured by surface micromachining.